

**ABSTRACT**

The present invention relates to a method and an apparatus for processing PFC, which does not damage a vacuum pump, and in which maintenance and inspection works  
5 are readily performed, and an incineration process is not required. The processing apparatus  
10 is constructed with a vacuum chamber 12, and a vacuum pump 16, a reaction gas  
introduction section 17, a plasma process section 18 and a polymer collection section 20 that  
are successively disposed through a piping 14 in a succeeding stage of the vacuum chamber  
12.

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